**User Information**

<table>
<thead>
<tr>
<th>Name *</th>
<th>Email *</th>
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**Registration Status** * I have completed the new user registration and turned in the appropriate forms to the UH Nanofabrication Facility's Administrator.

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**Training Request**

**Type**  - None - Facility Orientation
Atomic Force Microscope
Desktop Sputtering System
eBeam Evaporator
Beam Writer
Ellipsometer
Focused Ion Beam (FIB)
HF Training
Ion Mill
Mask
Aligner
Nanofab Inventory
Nanoimprinter
Optical Microscopes
profilometer
Rapid Thermal Processer
Reactive Ion Etcher (RIE 100)
Reactive Ion Etcher (RIE 180)
Reactive Ion Etcher (RIE 80)
Scanning Electron Microscope
Spin Coater
UHV Sputtering System
Vacuum Ovens

**Trainer:** Dr. Long Chang  
**Training Duration:** 0.5 hr

**Trainer:** Dr. Long Chang  
**Training Duration:** 2 hrs  
**Information:** You may bring your sample for the training.

**Trainer:** Dr. Jing Guo  
**Training Duration:** 0.5 hrs

**Trainer:** Dr. Jing Guo  
**Training Duration:** 2 hrs  
**Information:** Please specify the material you wish to evaporate in the comment box below.

**Trainer:** Dr. Long Chang  
**Training Duration:** 2 hrs  
**Information:** Trainees are required to use the equipment within two weeks of training. Please describe your substrate/sample and the patterns you wish to print in the comment box below.